

INFORMATION DISCLOSURE CITATION

Atty. Docket No. 07553.0029	Appln. No. 10/030,656	RECEIVED NOV 18 2002 TC 1700
Applicant Masaaki HAGIHARA et al.		
Filing Date 1/11/02	Group: Unknown 1763	

U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
<i>Aw</i>	6,107,208	8/22/00	Cheng et al.	438	724	

FOREIGN PATENT DOCUMENTS

Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
<i>Aw</i> EP 1 041 614 A1	10/4/00	EPO			Yes
<i>Aw</i> EP 0 993 031 A2	4/12/00	EPO			Yes
<i>Aw</i> EP 0 993 031 A3	5/3/00	EPO			Yes

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>Aw</i>	Ueno, K., et al., "Low Resistance Copper Via Technology," Advanced Interconnects and Contacts, San Francisco, CA, April 5-7, 1999, Materials Research Society Symposium Proceedings, Vol. 564, pp. 521-533
<i>Aw</i>	Wong, T.K.S., et al., "Fabrication of Sub-20 nm Trenches in Silicon Nitride Using CHF ₃ /O ₂ Reactive Ion Etching and Oblique Metallization," Journal of Vacuum Science and Technology: Part B, American Institute of Physics, New York, NY, Vol. 10, No. 6, pp2393-2397

Examiner <i>Alta w - Chen</i>	Date Considered 1/16/03
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	
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Examiner Initial*		Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate

FOREIGN PATENT DOCUMENTS							
		Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
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AWO		6-204191	07/22/1994	Japan	—		Abstract
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Examiner <i>Allan W. Ober</i>	Date Considered 1/14/03
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